



PbBi₄Te₇ and related compounds as new thermoelectric materials

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by

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■ PbBi₄Te₇ and related compounds

- Several compounds known
- MN₄Te₇ with M = Pb, Sn or Ge and N = Bi or Sb
- Limited information about thermoelectric properties
 - ◆ Most information for GeBi₄Te₇
 - ◆ Small band semiconductor

■ Crystal structure

- Layered compounds → anisotropy
- Unit cell contains 12 layers ; example : Te Bi Te Bi Te Te Bi Te Pb Te
- Hexagonal unit cell lattice parameters for PbBi₄Te₇ : a = 4.41 Å b = 72.09 Å
- Bonding predominantly covalent within the 12 layered stacks
 - ◆ May give high carrier mobility
- Van der Waals bonds between the 12 layered stacks
- Octahedral coordination
 - ◆ Potential for lattice thermal conductivity

■ Synthesis and characterization

- Melting, quenching and annealing
- X-ray and microprobe analysis
- TE measurements

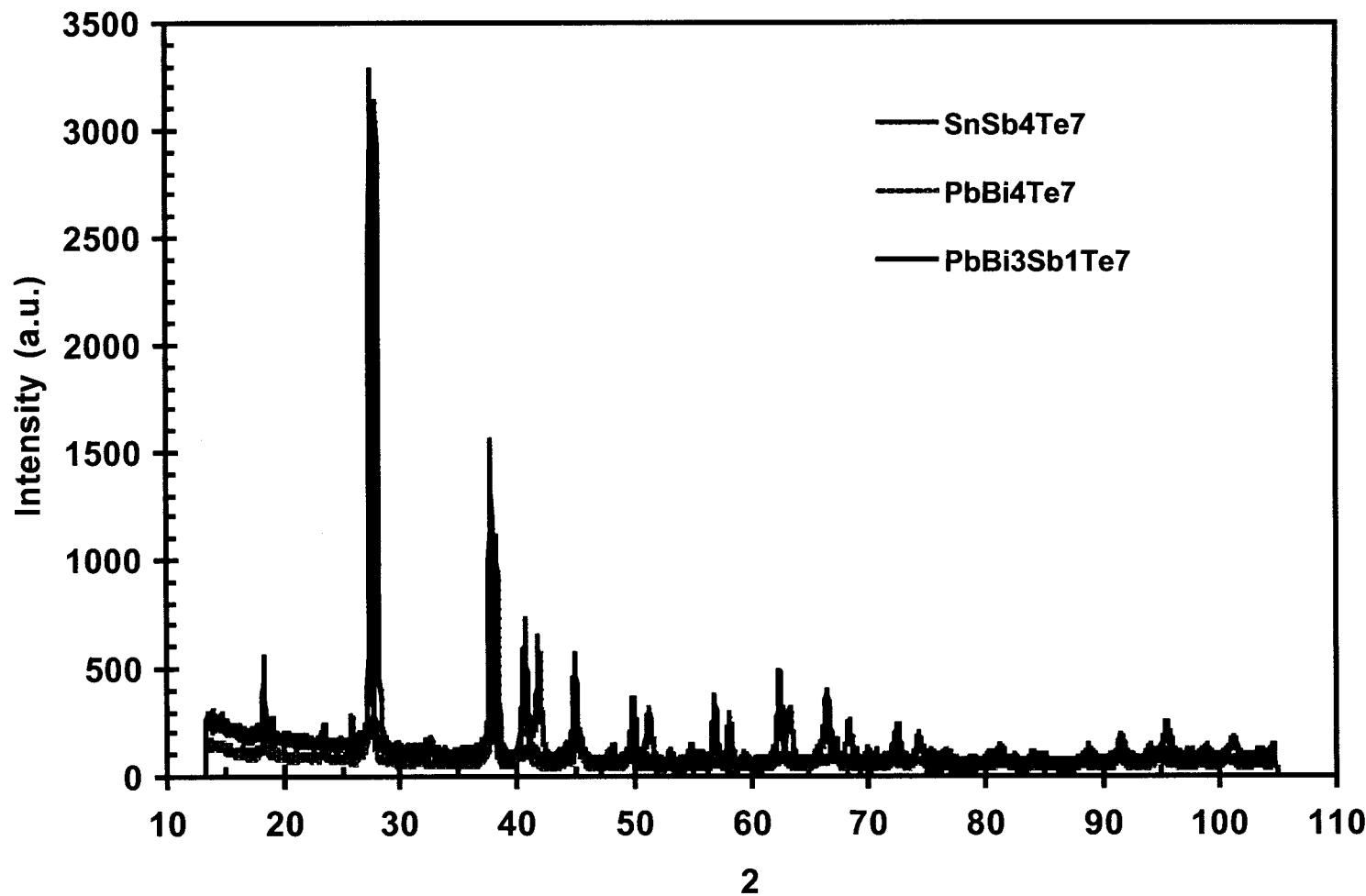
PbBi₄Te₇ and related compounds

Sample Label	Composition	CC ₃₀₀ cm ⁻³	μ _{H300} cm ² /Vs	ρ ₃₀₀ mΩ.cm	S ₃₀₀ μV/K
DM63	Sn ₁ Sb ₄ Te ₇				25.1
1DM63	cut per. pressing	9.63E+20	16.8	0.386	25.6
2DM63	cut par. pressing	8.65E+20	15.9	0.455	23.5
DM79	Pb _{0.5} Sn _{0.5} Bi ₂ Sb ₂ Te ₇				119.0
	cut per. pressing	1.16E+20	30.3	1.772	107.0
	cut par. pressing	1.05E+20	21.3	2.780	104.0
DM81	Pb _{0.5} Sn _{0.5} Bi ₃ Sb ₁ Te ₇				104.5
	cut per. pressing	1.13E+20	14.9	3.699	107.9
	cut par. pressing	8.71E+19	13.6	5.297	84.0

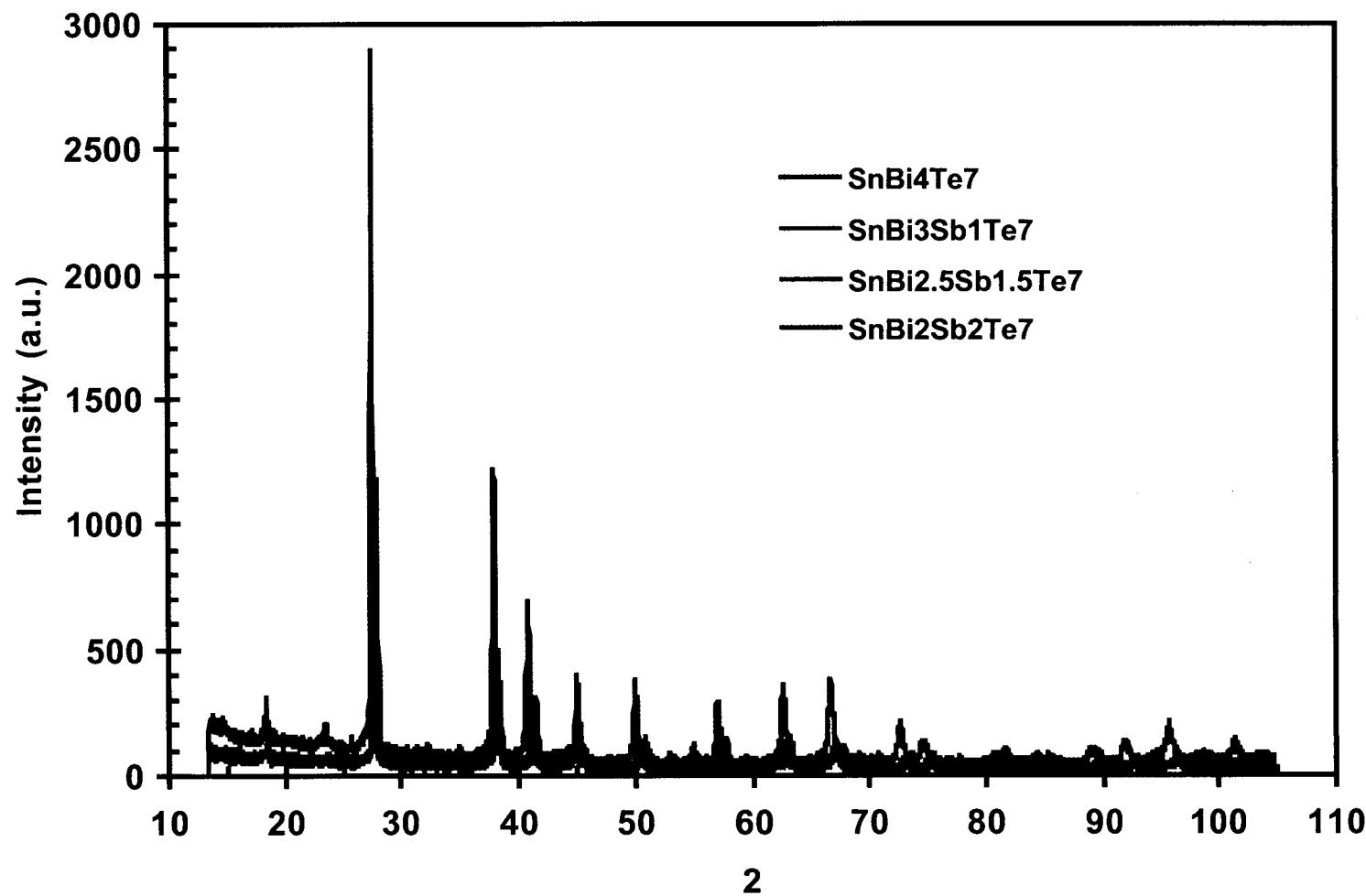
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DM65	Pb ₁ Bi ₄ Te ₇				-48.7
1DM65	cut per. pressing	2.72E+20	45.2	0.508	-53.4
2DM65	cut par. pressing	2.80E+20	36.5	0.612	-51.6
DM66	Pb ₁ Bi _{3.5} Sb _{0.5} Te ₇				-76.2
1DM66	cut per. pressing	1.62E+20	48.2	0.802	-74.6
2DM66	cut par. pressing	1.57E+20	39.3	1.017	-73.9
DM71	Pb ₁ Bi ₃ Sb ₁ Te ₇				-40.6
	cut per. pressing	1.06E+21	4.9	1.192	-38.6
	cut par. pressing	3.80E+21	1.0	1.662	-31.8
DM83	Pb ₁ Bi ₄ Te _{6.3} Se _{0.7}				-72.1
	cut per. pressing	1.65E+20	55.9	0.676	-76.2
	cut par. pressing	1.68E+20	41.1	0.906	-68.0

Sample Label	Composition	CC ₃₀₀ cm ⁻³	μ _{H300} cm ² /Vs	ρ ₃₀₀ mΩ.cm	S ₃₀₀ μV/K
DM64	Sn ₁ Bi ₄ Te ₇				95.4
1DM64	cut per. pressing	1.65E+20	13.3	2.843	102.3
2DM64	cut par. pressing	1.13E+20	14.9	3.710	90.3
DM76	Sn ₁ Bi ₃ Sb _{1.5} Te ₇				97.7
	cut per. pressing	9.99E+19	28.9	2.166	120.3
	cut par. pressing	9.39E+19	17.9	3.720	118.4
DM77	Sn ₁ Bi _{2.5} Sb _{1.5} Te ₇				99.3
	cut per. pressing	1.89E+20	30.5	1.083	94.7
	cut par. pressing	1.62E+20	28.3	1.360	90.2
DM78	Sn ₁ Bi ₂ Sb ₂ Te ₇				74.6
	cut per. pressing	2.62E+20	29.2	0.818	71.8
	cut par. pressing	2.16E+20	25.9	1.120	66.5
DM85	Sn ₁ Bi ₄ Te _{6.3} Se _{0.7}				148.0
	cut per. pressing	1.10E+20	16.0	3.540	142.9
	cut par. pressing	7.97E+19	17.6	4.452	139.6

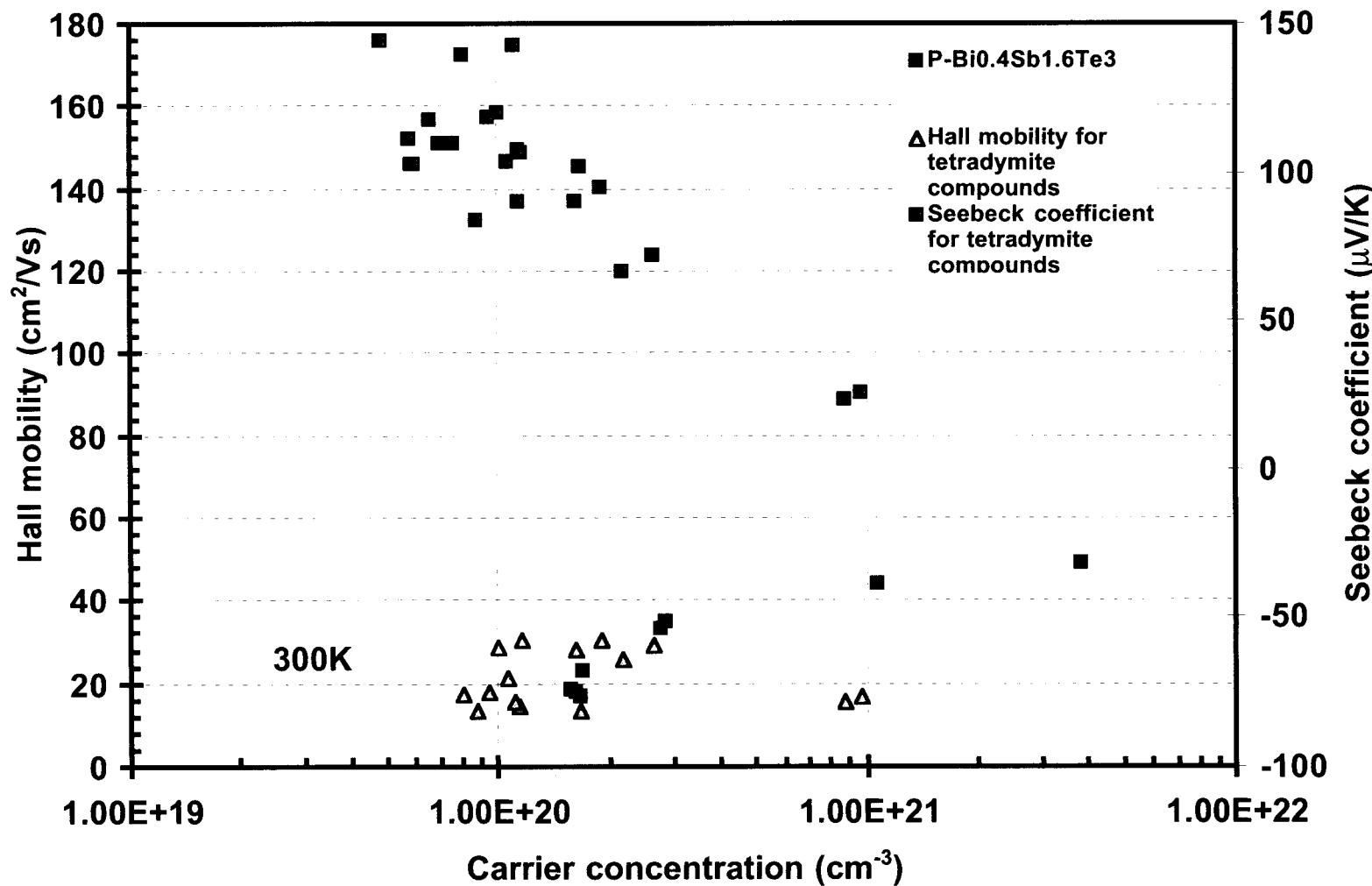
PbBi₄Te₇ and related compounds (continued)



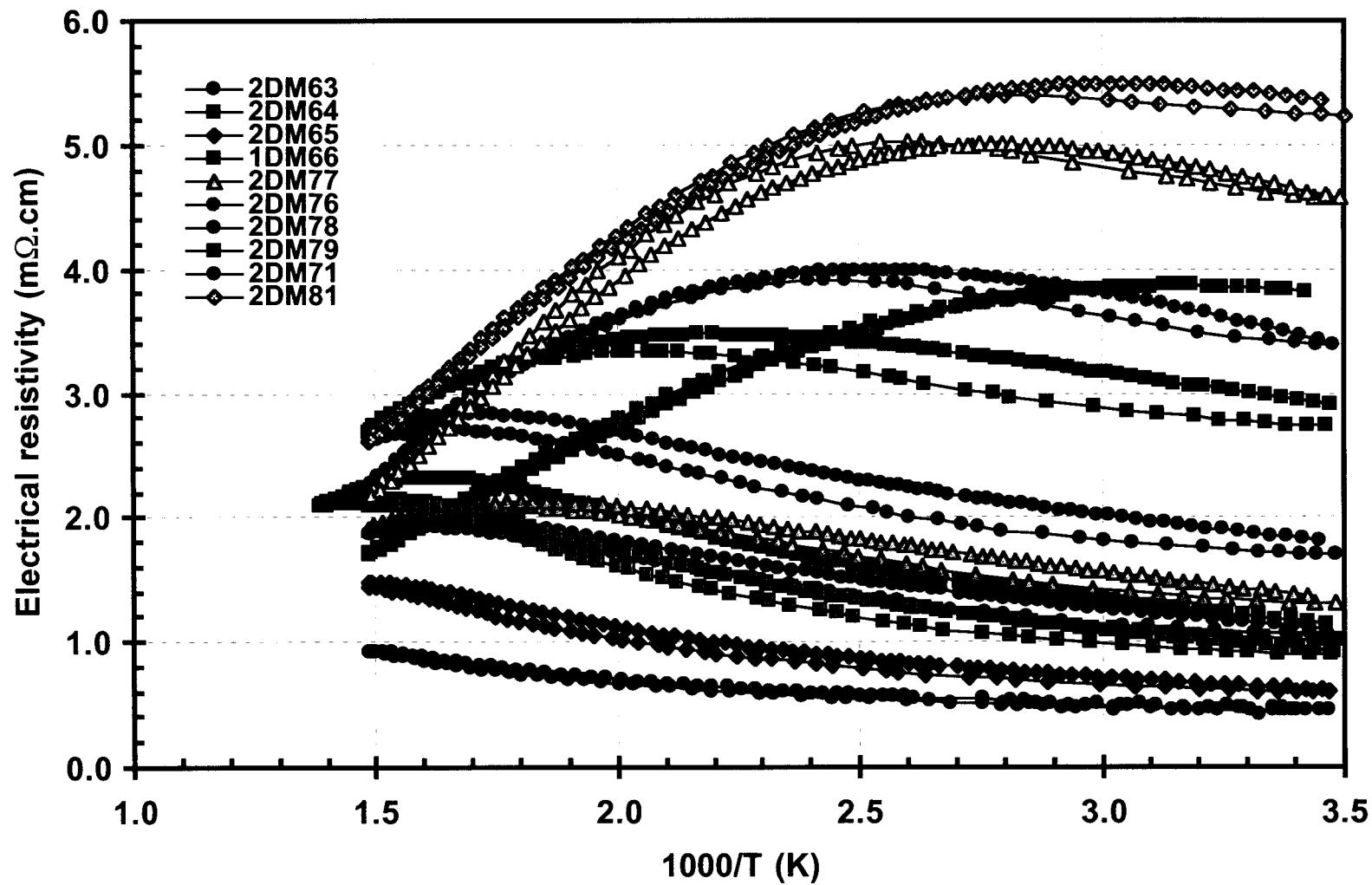
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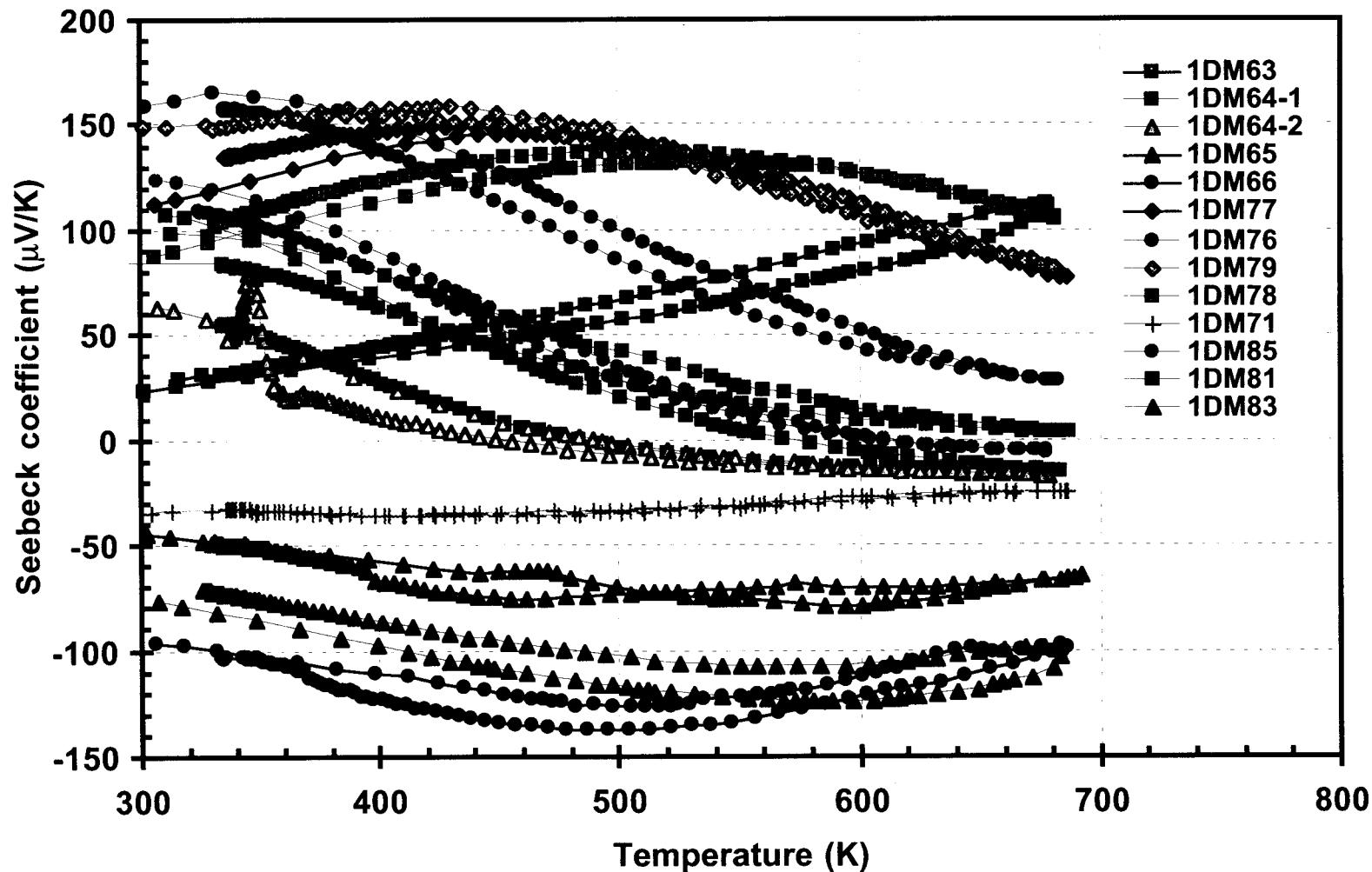
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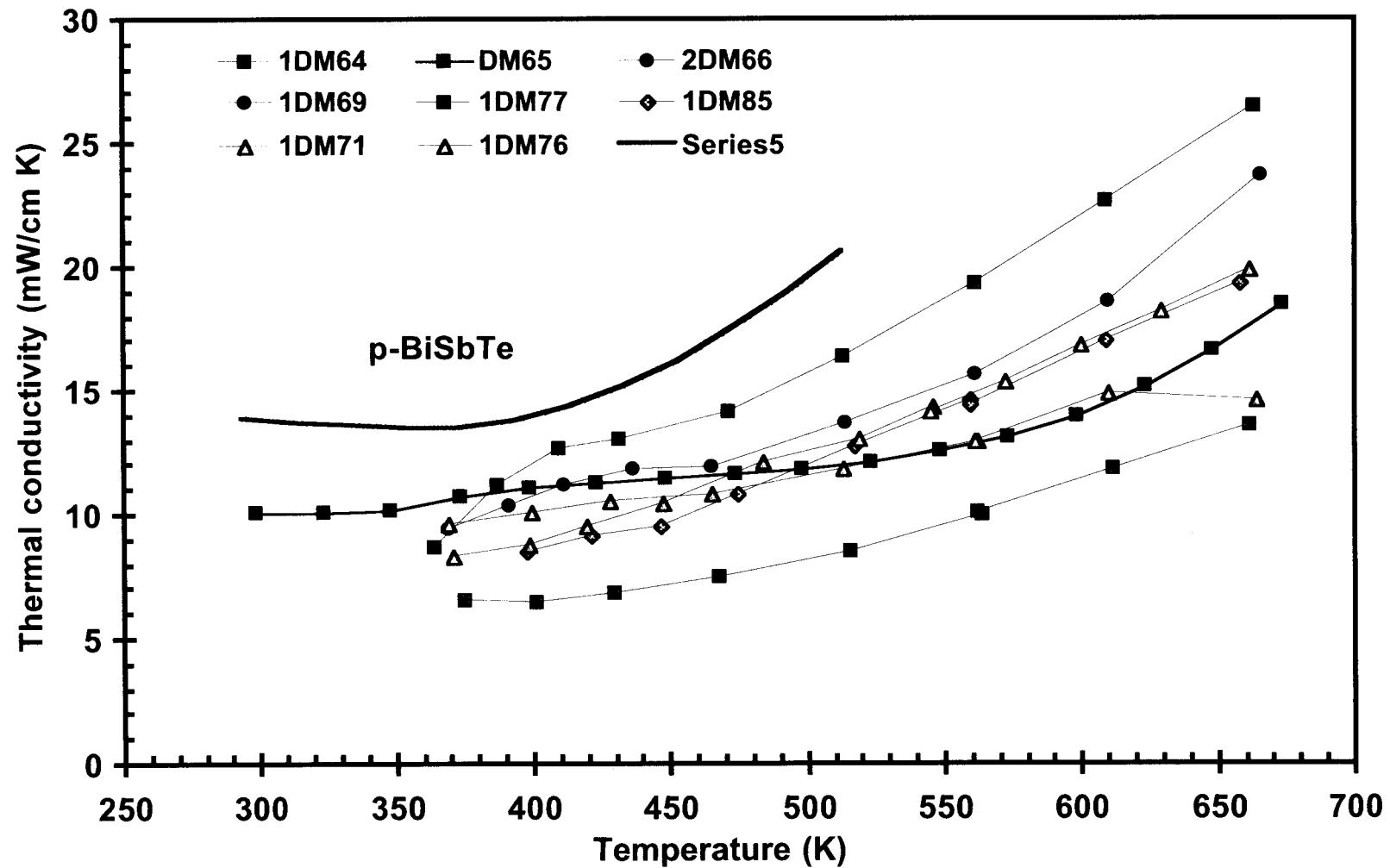
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